

EAST Search History

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|--------|---------------------------------------|--|------------------|---------|------------------|
| L6 | 285 | L5 and @pd>"20070101" | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/04/12 16:08 |
| S8 | 441 | S7 and @pd>"20060803" | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/04/12 16:07 |
| L5 | 6966 | 257/66,72,347.ccls. | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/04/12 16:07 |
| L4 | 121 | 3 and @py<"1992" | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/04/12 13:56 |
| L3 | 17897 | 2 and (pixel near2 electrode) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/04/12 13:56 |
| L2 | 32724 | 1 and (gate with substrate) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/04/12 13:55 |
| L1 | 127073 | (thin adj film adj transistor) or TFT | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/04/12 13:55 |

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| S37 | 50 | ((ALN or (aluminum near nitride)) with (layer or film)) with ((carbon)) with (stress or strain) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/03/05 18:22 |
| S36 | 1323 | S35 and substrate | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/03/05 18:22 |
| S35 | 1528 | ((ALN or (aluminum near nitride)) with (layer or film)) with ((carbon)) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/03/05 18:22 |
| S34 | 1660 | ((ALN or (aluminum near nitride)) with (layer or film)) with ((carbon or (C with O))) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/03/05 18:22 |
| S32 | 256 | S31 and substrate | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/03/05 18:22 |
| S33 | 3510 | ((ALN or (aluminum near nitride)) with (layer or film)) with ((carbon or C)) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/03/05 18:21 |
| S31 | 270 | ((ALN or (aluminum near nitride)) with (layer or film)) same ((carbon or C) with (doped or dopant or cotaminat\$6)) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/03/05 18:21 |

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| S30 | 59 | (ALN or (aluminum near nitride)) with (carbon with (stress or strain)) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/03/05 18:11 |
| S29 | 0 | (ALN or (aluminum near nitride)) with (barrier or passivat\$5) with (carbon with (stress or strain)) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/03/05 18:05 |
| S28 | 397 | (ALN or (aluminum near nitride)) with (barrier or passivat\$5) with (substrate or wafer) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/03/05 18:02 |
| S24 | 1800 | (ALN or (aluminum near nitride)) with (barrier) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/03/05 15:31 |